

Precursor Vapor Delivery Systems

# EpiSource™ with SMR

[www.cerestechnologies.com/en/our-products](http://www.cerestechnologies.com/en/our-products)

**EpiSource™** is a vapor-on-demand, fully automated, sub fab vapor delivery system for batch or multi-chamber CVD tools. Featuring our patented “SMR” vapor generator, **EpiSource™** be configured as a bubbler or flash evaporator to supply vapor to process tool MFCs. The system can also be configured for real-time refill from liquid delivery systems or on-board pressure vessel. EpiSource systems are designed to maintain stable concentration and pressure to feed multiple MFCs at a time.

## Why choose EpiSource™ with SMR ?

- On-demand vapor supply to multiple MFCs
- Stable vapor under variable flow rate conditions
- Supports short and or long process run times
- High capacity, on demand, near tool vapor supply
- Bubbler displays concentration and grams/min SEMI S2 compliant and QMS ISO9001-2018



EpiSource™ Single SMR

## Applications

**EpiSource™** enables remote supply of vapor on demand to one or more MFCs, or process tools. EpiSource™ is an alternative to direct liquid injection vaporizers that are limited to supplying one point of use. EpiSource™ is best suited for liquid precursors less than 120°C and less than 20 slm vapor flow rate, whether binary or neat vapor, such as TCS and SiCl<sub>4</sub>.

## Features

- Patented SMR vapor generation and supply
- Steady state vapor supply for long process runs
- On-board maintenance circuits for push gas, purge gas, vent and vacuum functions
- Optional on-board refill plumbing and scale
- Optional fire safety features for NFPA 79